

PATENT

ASMJP.126AUS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Akira Shimizu, et al.
App. No. : Unknown
Filed : Herewith
For : SINGLE-WAFER-PROCESSING TYPE
CVD APPARATUS
Examiner : Unknown
Group Art Unit : Unknown

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing references that are also enclosed. The listed references, except for "Technical Report" by John J. Sullivan et al., are described in the present specification, and to that extent, these references are relevant. "Direct Liquid Injection System" does not accompany an English translation; however the reference is described in the present specification and the contents of the reference are similar to "Technical Report" by John J. Sullivan et al. The publication dates of "Technical Report" and "Direct Liquid Injection System" are not established; however, Applicant possessed these references more than one year ago. This Information Disclosure Statement is being filed within three months of the filing date of this application or upon filing if this is a CPA or RCE, and no fee is required in accordance with 37 C.F.R. § 1.97(b)(1), (b)(2), or (b)(4).

Respectfully submitted,
KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: July 14, 2003

By: 
Katsuhiko Arai
Registration No. 43,315
Attorney of Record
Customer No. 20,995
(949) 760-0404

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMJP.126AUS	APPLICATION NO. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		
(USE SEVERAL SHEETS IF NECESSARY)		
APPLICANT Akira Shimizu, et al.	FILING DATE Herewith	
GROUP Unknown		

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
1.	6-316765	11/15/94	Japan (Pat. No. 3112721 issued 9/22/00)			abstract	
2.	2000-199067	07/18/00	Japan			abstract	
3.	2001-11634	01/16/01	Japan			abstract	
4.	2001-148347	05/29/01	Japan			abstract	

EXAMINER
INITIAL

OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

5. John J. Sullivan, et al. Optimization of the Copper Precursor Delivery for CVD Deposition Process, Technical Report, MKS Instruments, Inc. Andover, MA 01810, pages 1-6

6. Direct Liquid Injection System, Japan MSK, Nikko No. 97, 10.08.200.

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EXAMINER	DATE CONSIDERED
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*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.